

GAU 1764  
TENT 1/20/01  
Raf

ation of:

9/287,602

7, 1999

SCRUBBER FOR TREATING  
GAS GENERATED DURING  
SEMICONDUCTOR  
UFACTURING PROCESS

O I P E J C 1 0 4  
JAN 08 2001  
PATENT & TRADEMARK OFFICE

Group Art Unit: 1764  
Examiner: Varcoe, F.

Atty. Dkt. No. 5480-00200

**CERTIFICATE OF MAILING**  
**37 C.F.R. § 1.8**

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: **Box: Non-Fee Amendment,** Assistant Commissioner for Patents, Washington, D.C. 20231, on the date indicated below:

Kevin L. Daffer

**AMENDMENT; RESPONSE TO OFFICE ACTION DATED OCTOBER 4, 2000**

**Box: Non-Fee Amendment**  
Assistant Commissioner for Patents  
Washington, D.C. 20231

Dear Sir/ Madam:

This paper is submitted in response to the Office Action dated October 4, 2000 to further highlight reasons why the application is in condition for allowance.

Please amend the case as follows:

**In the Specification:**

Please replace the specification of the originally claimed case, excluding the claims, with the substitute specification in Attachment A. A “marked-up” copy of the original specification is included in Attachment B, showing the changes made to produce the substitute specification. The